

# Low Mass Mechanics and Cooling for Belle II Pixel Vertex Detector (PXD)

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8th Terascale Detector Workshop  
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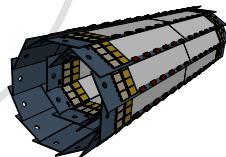


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(Werner-Heisenberg-Institut)

**DEPFET**



Introduction  
Mechanics and cooling Design  
Conclusions



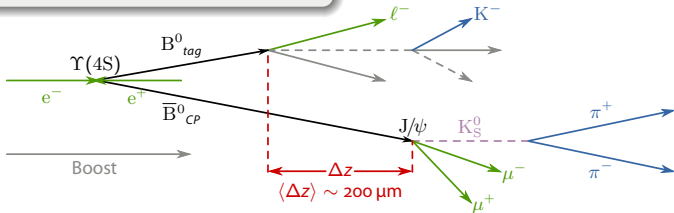
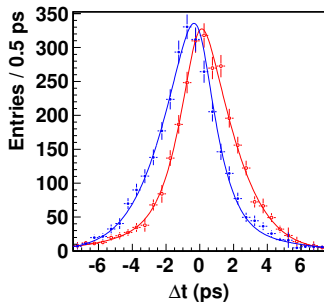
# Measurement of CP Violation

Measure time dependent decay asymmetry of  $B$  and  $\bar{B}$  going to the same final state

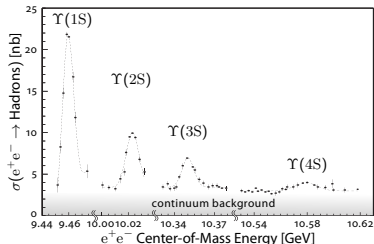
- ▶ lifetime of  $B$  mesons is 1.5 ps
- ▶ flavour of  $B$  meson has to be known

## Solution

- ▶  $\Upsilon(4S)$ : coherent  $B$ -meson pair production
- ▶ one  $B$  to determine flavour (tag side), other  $B$  for CP measurement (CP side)
- ▶ boost system using asymmetric beam energies  $t \rightarrow \Delta t = \frac{\Delta z}{\langle \beta \gamma \rangle c}$



# Experimental requirements



Best place to produce  $B\bar{B}$  in a clean environment is at the  $\Upsilon(4S)$ :

- ▶ lowest energy with free B mesons
- ▶ 1/3 of all hadronic events are  $B\bar{B}$
- ▶ possibility to “turn off” B production by lowering center of mass energy by 50 MeV

## Differences to LHC Experiments

Energy is factor  $\mathcal{O}(1000)$  smaller than at the LHC

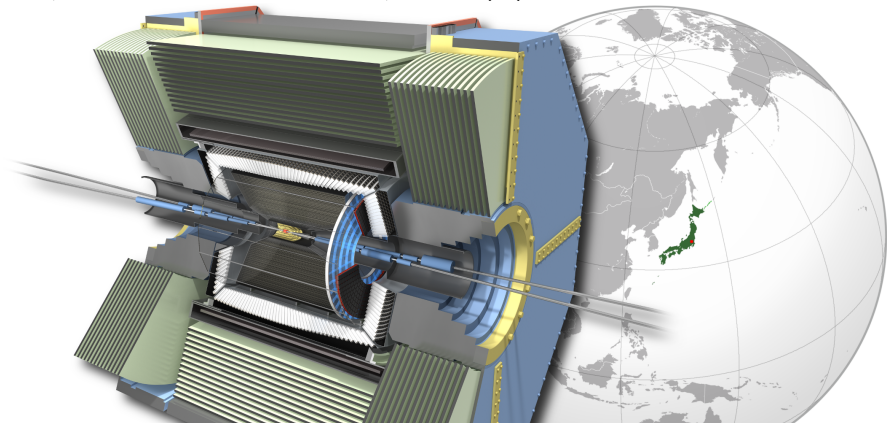
- ▶ mean momentum of charged particles is around 500 MeV
- ▶ tracking charged particles down to  $p_t \approx 50$  MeV

Electron Collider:

- ▶ full knowledge about the center of mass frame
- ▶ no underlying events
- ▶ but: lower cross section (more than factor 100)

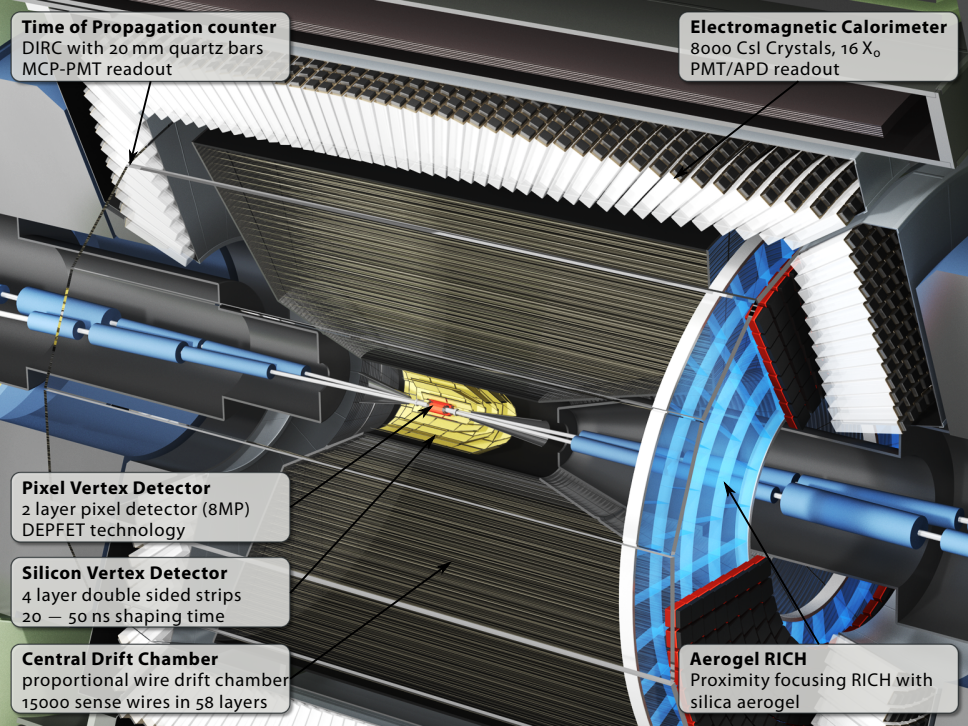
# Belle/Belle II Experiment

Asymmetric  $e^+e^-$  experiment mainly at the  $\Upsilon(4S)$  resonance (10.58 GeV)



	KEKB/Belle	SuperKEKB/Belle II
operation	1999 – 2010	2018 –
peak luminosity	$2.11 \times 10^{34} \text{ cm}^{-2} \text{ s}^{-1}$	$8 \times 10^{35} \text{ cm}^{-2} \text{ s}^{-1}$
integrated luminosity	$1023 \text{ fb}^{-1}$ (772 million $\text{B}\bar{\text{B}}$ pairs)	$50 \text{ ab}^{-1}$





The diagram shows a complex detector assembly with several layers. At the top, there are white, fan-shaped structures. Below these are blue cylindrical components. In the center, there is a yellow, grid-like structure. To the right, there are more white, fan-shaped structures. The entire assembly is housed in a dark grey, cylindrical container. Arrows point from the labels to the corresponding components.

**Time of Propagation counter**

DIRC with 20 mm quartz bars  
MCP-PMT readout

**Electromagnetic Calorimeter**

8000 CsI Crystals, 16  $X_0$   
PMT/APD readout

**Pixel Vertex Detector**

2 layer pixel detector (8MP)  
DEPFET technology

**Silicon Vertex Detector**

4 layer double sided strips  
20 – 50 ns shaping time

**Central Drift Chamber**

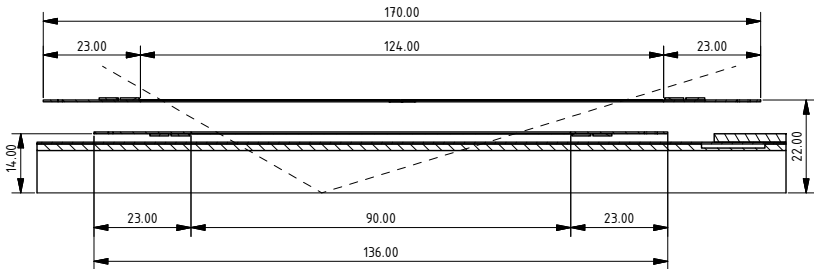
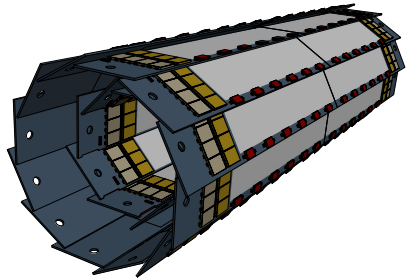
proportional wire drift chamber  
15000 sense wires in 58 layers

**Aerogel RICH**

Proximity focusing RICH with  
silica aerogel

# Pixel Vertex Detector (PXD)

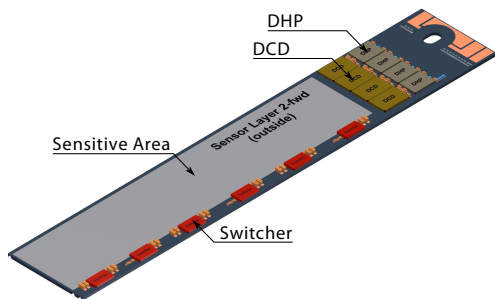
- ▶ innermost part of the detector
- ▶ covers acceptance of  $17^\circ < \theta < 150^\circ$
- ▶ 2 layer pixel detector with 40 DEPFET sensors (7.68 million pixels)
- ▶ readout time of 20  $\mu\text{s}$
- ▶ data rate of 240 Gb/s = 30 GB/s
- ▶ pixel size from  $50 \times 55 \mu\text{m}$  to  $50 \times 85 \mu\text{m}$
- ▶ total material budget of 0.28 % $X_0$



# Sensors and Power Consumption

DEPFET pixel sensors (details by Ladislav Andriček)

- ▶  $250 \times 768$  pixels
- ▶ sensitive area size:  
 $12.50 \text{ mm} \times 44.80 \text{ mm}$  (layer 1)  
 $12.50 \text{ mm} \times 61.44 \text{ mm}$  (layer 2)



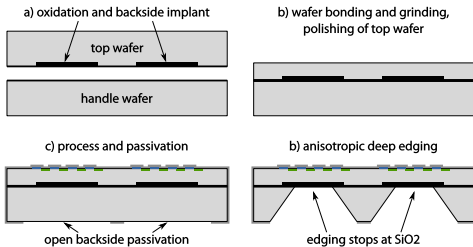
Three different ASICs on the sensors:

Name	Purpose	Position	Power consumption
DCD	Signal digitization	end of sensor	4 W
DHP	Digital signal processing	end of sensor	4 W
Switcher	Row addressing	along sensor	0.5 W

- ▶ sensitive area has power consumption of 0.5 W
- ▶ power consumption dominated by end of sensor (8 W)
- ▶ no need for extensive cooling inside acceptance

# Sensor Thinning

- ▶ sensitive area will be thinned down to  $75\ \mu\text{m}$
- ▶ integrated support frame to keep stability



- ▶ additional mass reduction by edging brick structure into frame

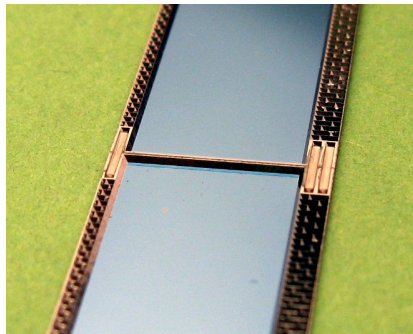


# Ladder Design



## Ladder formed from 2 sensors

- ▶ ladders are **self supporting**
  - ▶ butt-face joint glueing
  - ▶ reinforced with ceramic inserts
  - ▶ almost no additional material
  - ▶ only 850  $\mu\text{m}$  dead area
- ➔ extensive stability studies
- ➔ 4 types of different sensors



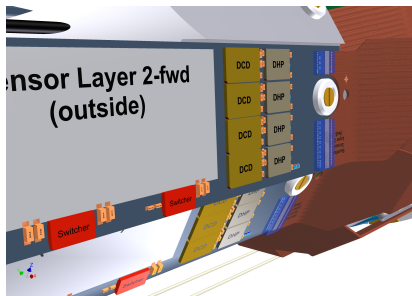
# Ladder Assembly



## Ladders screwed on support

- ▶ elongated hole on one side
- ▶ M1.2 screw with plastic washer
- ▶ o-ring to prevent contact between screw and silicon
- ▶ torque of 15 mNm

➔ torque allows for compensating of thermal expansions

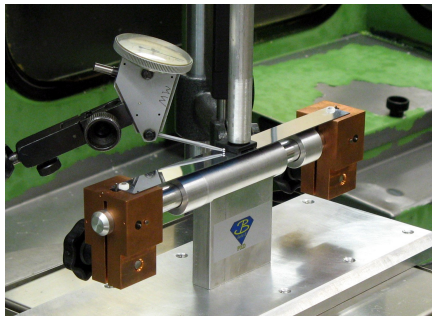


# Stability studies



## tensile strength tests carried out

- ▶ single piece of silicon tested up to 7 kg
- ▶ gluing of unthinned silicon stable to 6 kg
- ▶ gluing of 50  $\mu\text{m}$  thin silicon survived 5 kg



## deformation tests

- ▶ single piece of silicon breaks at 1.4 mm
- ▶ no problems up to 1 mm deformation

# Cooling Concept

## Requirements

- ▶ total system power is 360 W (80 W in sensitive region)
- ▶ silicon temperature below 25 °C
- ▶ chip temperature below 50 °C

## End of sensor:

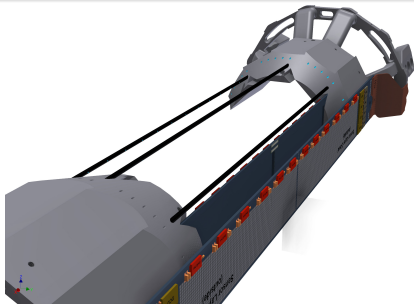
- ▶ 2-phase  $CO_2$  cooling system
- ▶ joint development with ATLAS IBL
- ▶ provide  $-20$  °C below end of sensor to cool ASICs

## Along the sensor:

- ▶ provide moderate airflow (1 m/s at  $-5$  °C) to cool Switcher and sensitive area



# Support

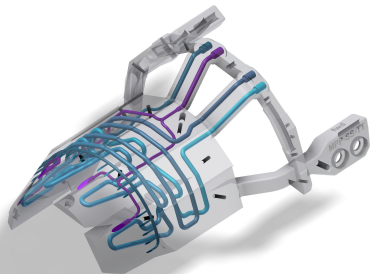


manufactured using 3D printing technology

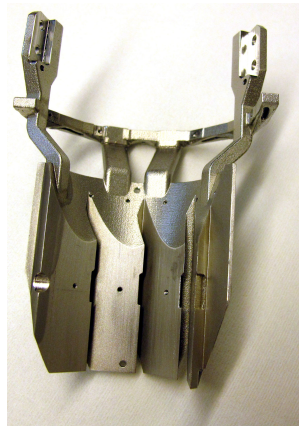
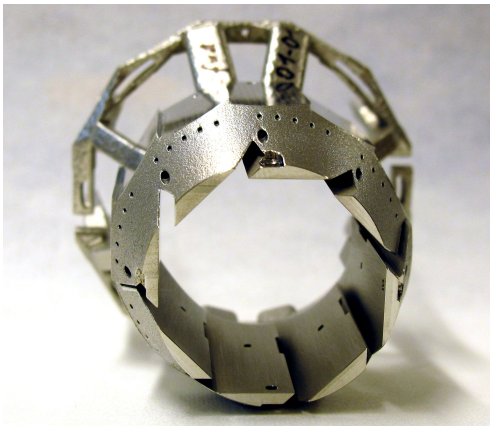
- ▶ stainless steel
- ▶ integrated cooling channels
- ▶ closed  $\text{CO}_2$  channel to cool end of sensors
- ▶ nitrogen channels to provide airflow
- ▶ coated with  $15\ \mu\text{m}$  Parylen

The PXD will be mounted directly on the beampipe

- ▶ assemble in two half shells
- ▶ one common support for both layers
- ▶ combined support and cooling blocks (SCB) per detector half
- ▶ connected by silver coated carbon fiber tubes for air cooling and grounding



# SCB Prototypes



## Final SCB Prototypes

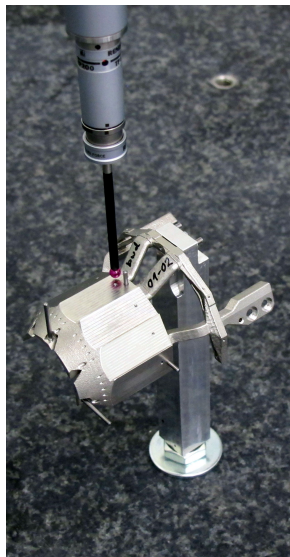
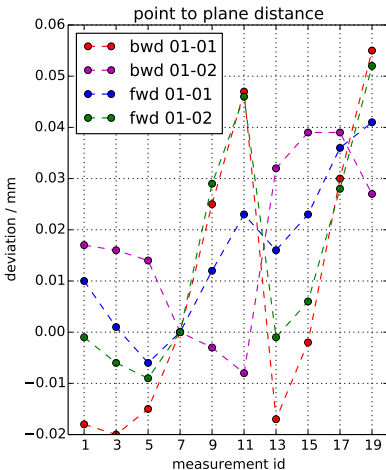
- ▶ precision machining of surfaces
- ▶ roughness  $R_a$  around  $0.25 \mu\text{m}$
- ▶ flatness better than  $7 \mu\text{m}$

All cooling channels operational

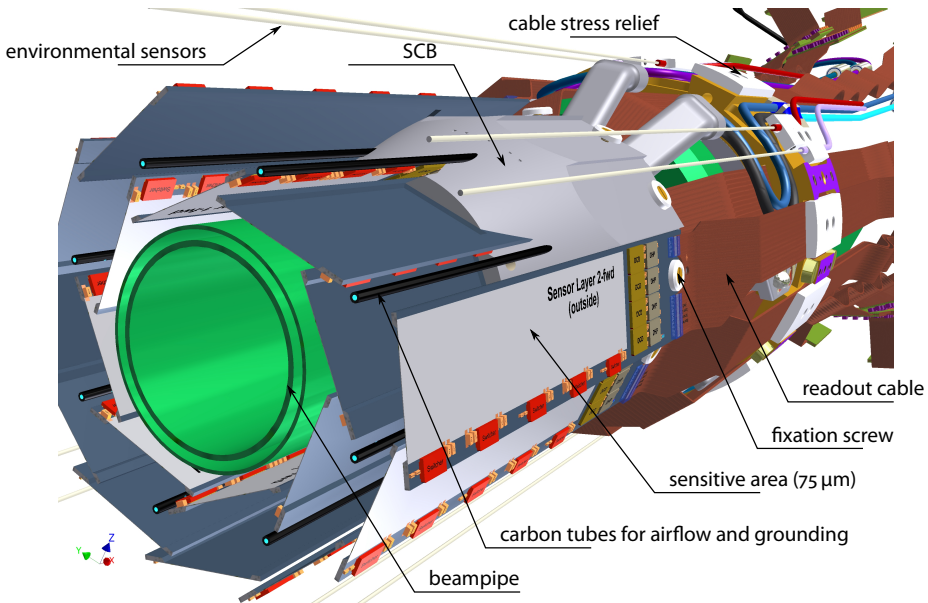
- ▶ pressure tested with 186 bar for 1 h
- ▶ helium leakage smaller than  $10^{-9}$  mbar/s

# Measurement of SCB Prototypes

- ▶ measured relative distances between surfaces
- ▶ deviations from nominal mostly around 20  $\mu\text{m}$



## Full System (Cut View)



# Conclusions

## Belle II Pixel Vertex Detector

- ▶ self supporting silicon detector
- ▶ sensitive area thinned to 75  $\mu\text{m}$
- ▶ power dissipation mostly outside of geometrical acceptance
- ▶ combined support and cooling blocks (stainless steel, 3D printed)
- ▶ total material budget of 0.28  $\%X_0$

## Cooling

- ▶ 2-phase  $\text{CO}_2$  cooling system to cool chips
- ▶ joint development with ATLAS IBL
- ▶ moderate airflow between sensors to cool sensitive area
- ▶ virtually no additional material from cooling inside acceptance

## Outlook and schedule

- ▶ optimizing and refining ladder assembly/handling procedures
- ▶ start full ladder assembly beginning 2016
- ▶ ready for system tests and integration by March 2017



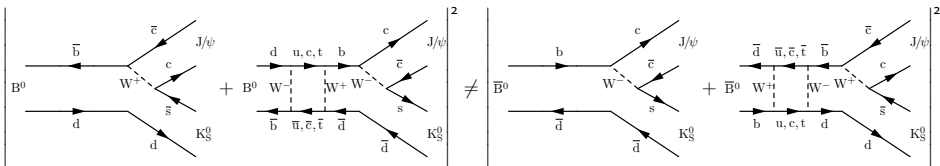
# Measurement of CP Violation

Objective: Measure time dependent decay asymmetry of  $B$  and  $\bar{B}$  going to the same final state

$$a_{CP}(t) = \frac{\Gamma(\bar{B}^0 \rightarrow f_{CP}; t) - \Gamma(B^0 \rightarrow f_{CP}; t)}{\Gamma(\bar{B}^0 \rightarrow f_{CP}; t) + \Gamma(B^0 \rightarrow f_{CP}; t)}$$

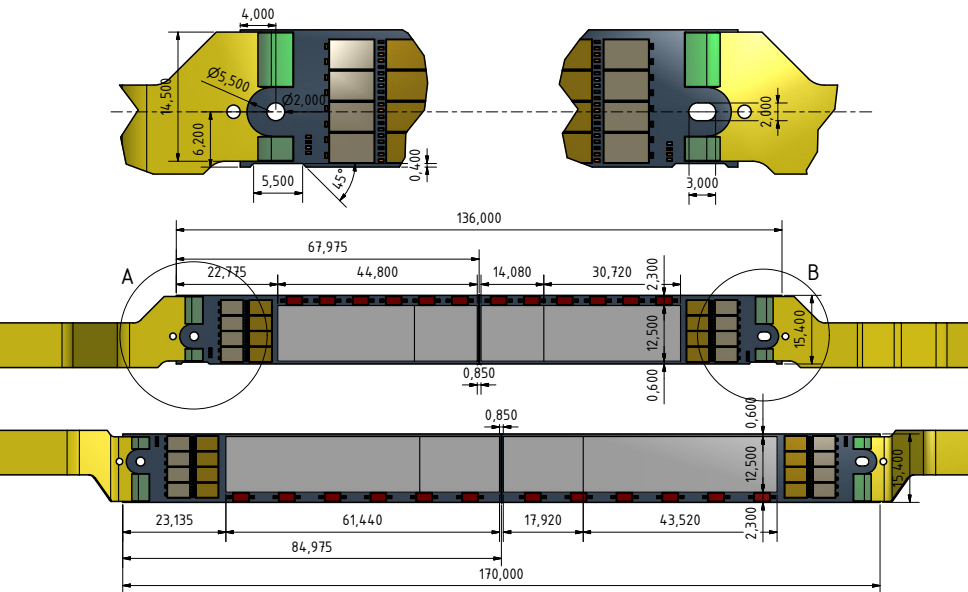
## 3 possible contributions

- ▶ CP violation in decay (direct)
- ▶ CP violation in mixing (indirect)
- ▶ CP violation by interference of mixing and decay (mixing induced)



- ▶ For  $B$  mesons, contributions from indirect CP violation are negligible
- ▶ For many decays, loop diagrams contribute to the amplitudes
  - ➡ possibility to indirectly detect new physics

# Ladder Dimensions





# Particle Contamination of Cooling Channels

Cooling channels were cleaned after manufacturing

- ▶ blow N<sub>2</sub> into cooling channels
- ▶ measure particle contamination at outlet
- ▶ probe volume 0.1 ft<sup>3</sup>/min

particle size	contamination	N <sub>2</sub> line
0.5 μm	9000–15000	8000
0.7 μm	4000–8000	3000
1.0 μm	2000–4000	1000
2.0 μm	300–1500	200
5.0 μm	20–80	30

